

Electronic Acknowledgement Receipt

EFS ID:	1415779
Application Number:	10750845
International Application Number:	
Confirmation Number:	3873
Title of Invention:	Photoresist composition for multi-micro nozzle head coater
First Named Inventor/Applicant Name:	Sung-Chul Kang
Customer Number:	23413
Filer:	Dana Gronbeck/Kim Padilla
Filer Authorized By:	Dana Gronbeck
Attorney Docket Number:	YOM-0205
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Application Type:	Utility

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File Listing:

Document Number	Document Description	File Name	File Size(Bytes)	Multi Part /.zip	Pages (if appl.)
1		YOM0205_Amend_Resp.pdf	1270176	yes	13

Multipart Description/PDF files in .zip description			
Document Description		Start	End
Amendment - After Non-Final Rejection		1	1
Claims		2	5
Applicant Arguments/Remarks Made in an Amendment		6	13

Warnings:

Information:

Total Files Size (in bytes):	1270176
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New Applications Under 35 U.S.C. 111
 If a new application is being filed and the application includes the necessary components for a filing date (see 37 CFR 1.53(b)-(d) and MPEP 506), a Filing Receipt (37 CFR 1.54) will be issued in due course and the date shown on this Acknowledgement Receipt will establish the filing date of the application.

National Stage of an International Application under 35 U.S.C. 371
 If a timely submission to enter the national stage of an international application is compliant with the conditions of 35 U.S.C. 371 and other applicable requirements a Form PCT/DO/EO/903 indicating acceptance of the application as a national stage submission under 35 U.S.C. 371 will be issued in addition to the Filing Receipt, in due course.